

ABSTRACT

Embodiments of the present disclosure provide an ellipsometry device and a method for obtaining information of a surface of an object to be measured. The
5 ellipsometry device comprises: a polarized light beam providing device configured to provide a plurality of parallel polarized light beams; a first off-axis parabolic mirror configured to reflect the plurality of parallel polarized light beams such that a plurality of reflected first light beams are focused on a target point on a surface of an object to be measured, an included angle between each polarized light beam and
10 a corresponding first light beam being an acute angle; a second off-axis parabolic mirror configured to reflect a plurality of second light beams formed of the reflected first light beams reflected by the surface of the object to be measured, so as to form a plurality of parallel third light beams, an included angle between each second light beam and a corresponding third light beam being an acute angle; and a polarization
15 analysis device configured to analyze the polarization of the plurality of parallel third light beams. The embodiments of the present disclosure can significantly reduce the incident angle of a polarized light beam incident on an off-axis parabolic mirror, thereby effectively ensuring the polarization state of the polarized light beam.